



TEL Clean Track ACT8 SYSTEM

(RNX20200226-03)

2020.02.26



TEL Clean Track ACT8 System

Wafer Specification

Wafer Size	200mm	Description	Coater - Developer
Model	ACT8	Vintage	2007

System Configuration

UNC : Uni-Cassette Stage

HHP : High Temperature Station

ADH : Adhesion Process Station

LHP : Low Temperature Station

COT : Coat Process Station

SHU : Shuttle

TRS : Transition Stage

CPL : Cool Plate

DEV : Develop Process Station

TCP : Transition Chill Plate

WEE : Wafer Edge Exposure Process Station

PHP : Precision Hot Plate Process Station

TEL Clean Track ACT8 System

System Configuration

1-4 UNC	1-0 CRA	2-24 LHP		2-14 LHP	3-24 HCH		3-14 LHP	4-4 WEE	
		2-23 LHP		2-13 LHP	3-23 CHP		3-13 LHP		
		2-22 LHP		2-12 LHP	3-22 CHP		3-12 LHP		
		2-21 CPL		2-11 CPL	3-21 CHP		3-11 CPL		
		2-20		2-10 CWH	3-20		3-10		
1-3 UNC		2-19 CPL	2-29	2-09 CPL	3-19 CHP	3-29 LHP	3-09 CPL	4-0 IRA	4-5 EIS
		2-08 TRS	2-28	2-18		3-28 LHP	3-18		
		2-07 TCP	2-27	2-17		3-27 HHP	3-17 CPL		
1-2 UNC		2-06	2-26 LHP	2-16	3-6	3-26 LHP	3-16 TRS		
		2-05 ADH	2-25 LHP	2-15 ADH	3-05 CPL	3-25 LHP	3-15 CPL		
1-1 UNC	3-0 PRA			2-0 PRA					
	2-3 COT		2-4 COT	3-3 DEV		3-4 DEV			
	2-1 COT		2-2 COT	3-1 DEV		3-2 DEV		4-3 Buffer	
1-5 PUP								4-2 Buffer	
								4.1 T. Hold	

TEL Clean Track ACT8 System

System Configuration

External Tool

- 1). Chemical Cabinet #1**
- 2). Chemical Cabinet #2**
- 3). T & H Controller #1 (Team Korea)**
- 4). Thermo Controller Unit #1 (SMC)**
- 5). Thermo Controller Unit #2 (SMC)**
- 6). AC Power Box**

Machine Detail Information

- 1). Description**
 - 1-1. Left to Right System**
 - 1-2. Wafer & Carrier Type : 8 inch Notch, 25 Slot**
 - 1-3. System Power : AC208V, 3 Phase**
 - 1-4. Loading Configuration : 4 Loader Uni-Cassette**
 - 1-5. Software Version : Unknown**
 - 1-6. Main Controller : Missing**

TEL Clean Track ACT8 System

Machine Detail Information

2-1). Carrier Station

- Type : Normal Uni-Cassette
- 4 Cassette Stage, 1 Pick-up Cassette
- Uni-Cassette System

2-2). Coater Unit (2-1, 2-2, 2-3, 2-4)

- 3 Dispense Nozzle with Temperature Controlled Line for Etch Unit
- RDS Pump
- Rinse Nozzle : Back / EBR / Solvent Batch for Etch Unit
- Rinse System : 3 Litter 2 Tank Buffer Tank System
- P.R Suck-Back Valve Type : AMC Suck-Back Valve
- Programmable Side Rinse
- Drain : Direct Drain

2-3). Developer Unit (3-1, 3-2, 3-3, 3-4)

- 1 Nozzle for Each Unit
- 2 Stream Nozzle for DI Rinse and 2 Point for Back Side Rinse on Each Unit

TEL Clean Track ACT8 System

Machine Detail Information

- Developer System : 3 Litter 3 Tank Buffer Tank System
- Developer Temperature Control System
- Drain : Direct Drain

2-4). Interface Type : Nikon

2-5). Adhesion Unit : 2 Unit

- 100% Sealing Closed Chamber (Built-in Hot Plate)
- HMDS Tank with Float Sensor in System

2-6). Low Temp Hot Plate : 16ea

2-7). High Temp Hot Plate : 1ea

2-8). Chill Plate (CPL) : 9ea

2-9). Chilling Hot Plate Process Station (CHP) : 4ea

2-10). TCP Module : 1ea

2-11). TRS Module : 3ea

2-12). WEE (Wafer Edge Exposure) Module : 1ea

2-13). Chemical Cabinet #1, Chemical Cabinet #2

TEL Clean Track ACT8 System

Machine Detail Information

2-15). T/H Controller : 1ea

- Type : Team Korea

2-16). TEMP Control Unit (TCU) : 2ea

- Type : TEL OEM

2-17). AC Power Box

Missing Parts

-.Main Controller

-.Coater Cup x 4ea (2-1, 2-2, 2-3, 2-4)

-. Developer Cup x 3ea (3-1, 3-2, 3-3)

-. Main Display Panel

-. CRA X-Axis Motor

-. CSB Add on Board

-. Coater PR Pump x 9ea (2-1, 2-2, 2-3, 2-4)

-. IRA Y-Axis Motor Driver, IRA Tweezers

-. LHP Module Cover (All)

TEL Clean Track ACT8 System



Machine no.



CSB Board Area



Coater Module (2-1)



Coater Module (2-2)



Coater Module (2-3)



Coater Module (2-4)



RDS Pump



PR Pump Area



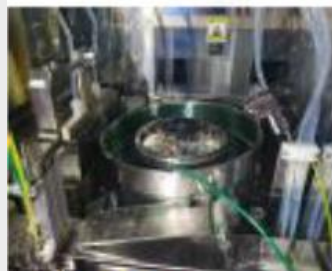
COT Chemical Area(L)



COT Chemical Area(R)



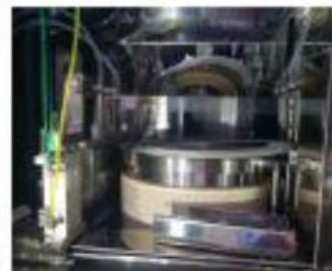
Shuttle



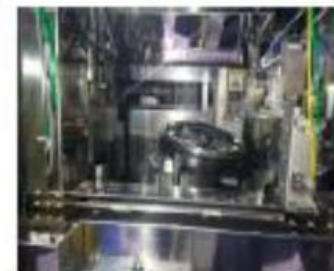
DEV Module (3-1)



DEV Module (3-2)



DEV Module (3-3)



DEV Module (3-4)

TEL Clean Track ACT8 System



DEV Nozzle



CRA



PR Cabinet



PR Bottle Area



Chemical Cabinet



Buffer Tank



Solvent Filter Area



Degas Module



DEV Filter Area



PRB2



IRA



T&H Controller



AC Power

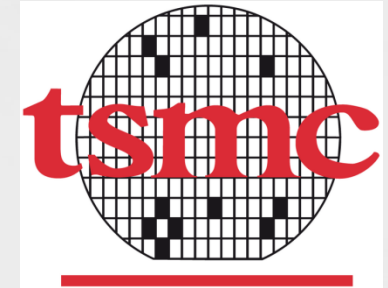


thermo Controller #1 , 2



EBR Flowmeter

RenoNix Major Customer



Contact

We're Capable of Most of service for PVD,CVD, ETCH areas.
If you have any inquiry or interest , please feel free to contact us.



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